

Surface Roughness and XRD Studies of Electron Beam Evaporated Mo and Er Films: correlation to substrate and process conditions

Loren Espada, Dan Kammler, Rob Ferrizz, Elaine Boespflug
Luke Brewer, Mark Rodriguez, Kim Archuleta and Michael
Eatough

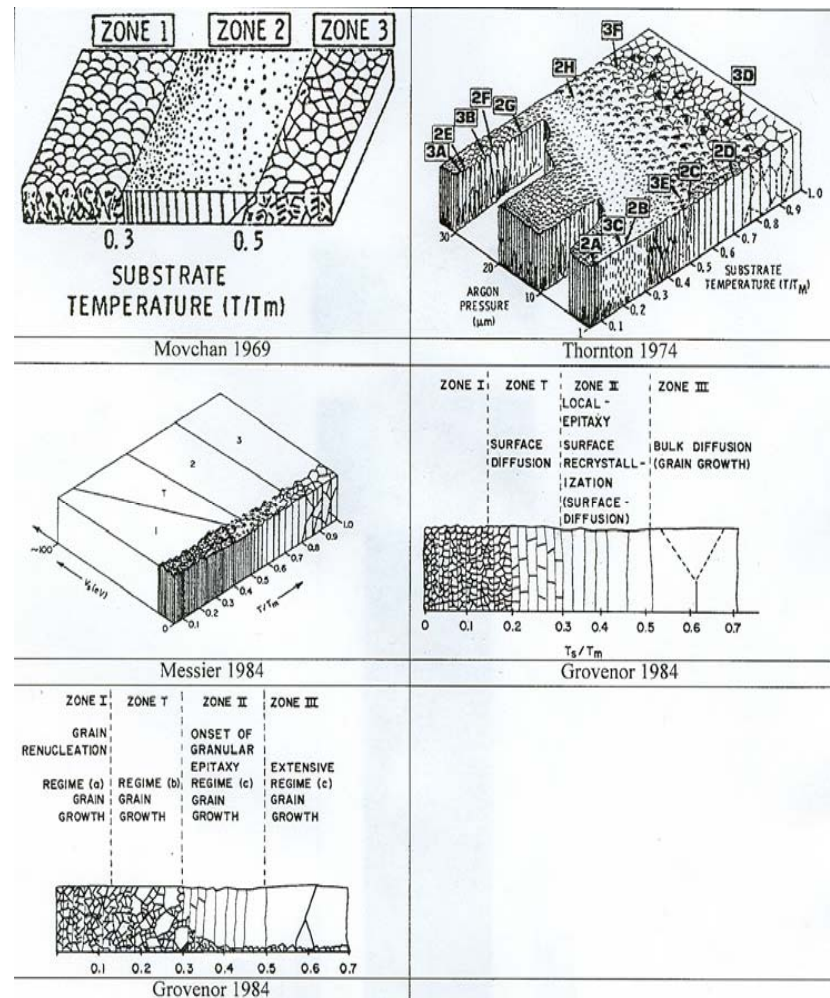
What do we measure

Grain Size orientation - Texture

Surface Roughness

Growth of Thin Films

- **Zone I** - $T_s/T_m < 0.3$ (low mobility; ad-molecules stick where they land: the results is a fine-grained porous real structure).
- **Zone II** - $0.3 < T_s/T_m < 0.5$ (surface diffusion occurs with activation energies of 0.1-0.3 eV; a columnar real structure is obtained).
- **Zone III** - $T_s/T_m > 0.5$ (bulk diffusion occurs with activation energies above 0.3 eV, resulting in a rough equiaxed grained real structure).





Importance of Process Conditions

- Deposition Conditions
 - Temperature, rate, atoms, energy, residual gases
- Substrate surface Morphology
 - Material Real Structure
 - Grain size, orientation, defect density
- Film Properties
 - Electronic, Magnetic, Optical, Mechanical

Process Conditions

Substrate	Texture	Surface Finish
Si	(100)	smooth
Al ₂ O ₃	[1-102]	smooth
Rolled Mo	Rolled	rough

Deposition Temperature	RT 250°C 450°C
Deposition Rate	1.0 Å/s 10 Å/s



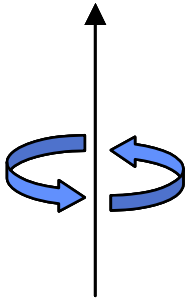
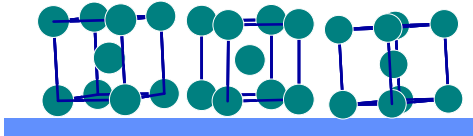
Summary of Samples

Substrate	Film	Thickness (Å)	Temperature °C	Deposition Rate (Å/s)
[1-102] Al ₂ O ₃	Mo	1000	250	1
Mo/[1-102] Al ₂ O ₃	Er	5000	450	10
No-Etched Mo	Er	5000	450	10
Etched Mo	Er	5000	450	10
Si(100)	Mo	1000	RT	1

Texture Definitions

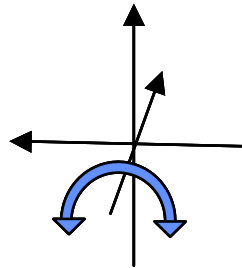
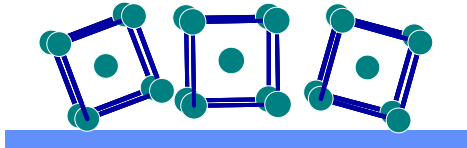
Fiber

out-of-plane (YES)
in-plane (NO)



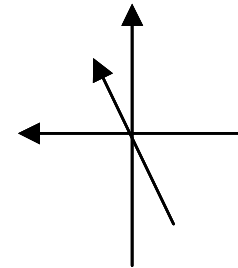
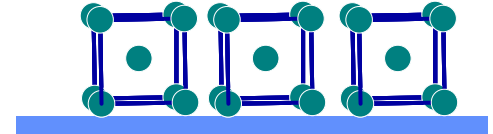
Rolling Texture

out-of-plane (YES)
in-plane: 1-dimension of
freedom, other fixed



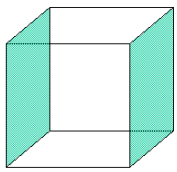
Bi-Axial

out-of-plane (YES)
in-plane (YES)

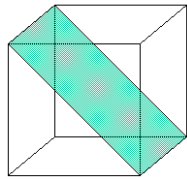


Courtesy of Mark Rodriguez

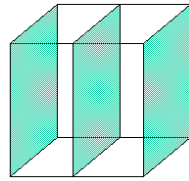
Pole figure represents a distribution in space of a given set of lattice planes (hkl)



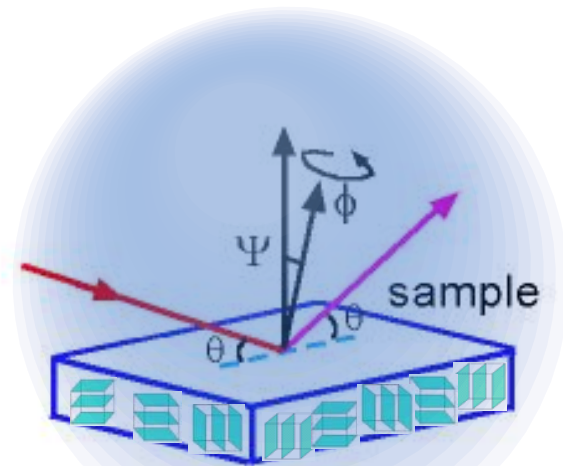
(100)



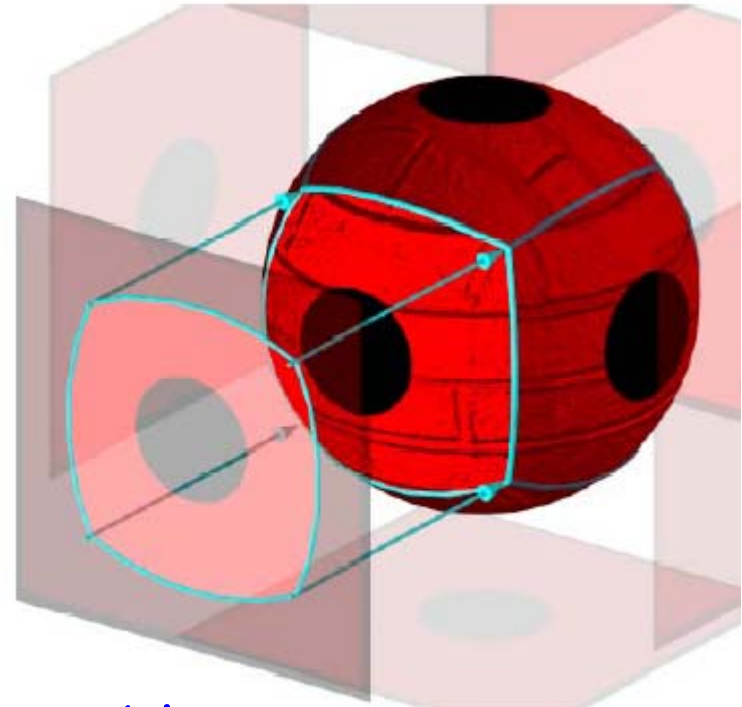
(110)



(200)



Pole Figure Measurement

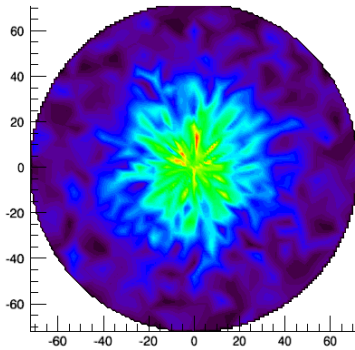


All possible orientations of the given hkl are plotted on a hemisphere which is projected onto a planar surface

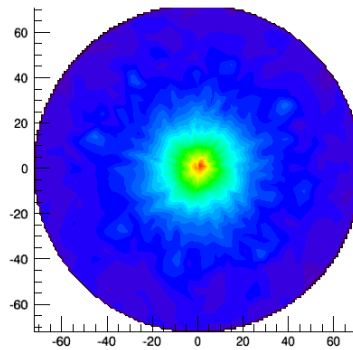
The Influence of Substrate Texture on Mo Films Grain Orientation

RT, 1000 Å, 1 Å/s

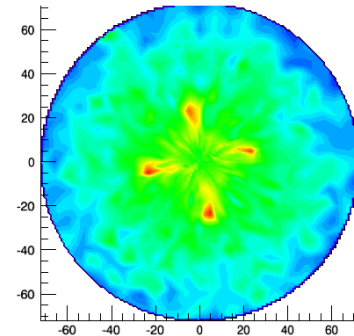
110



211

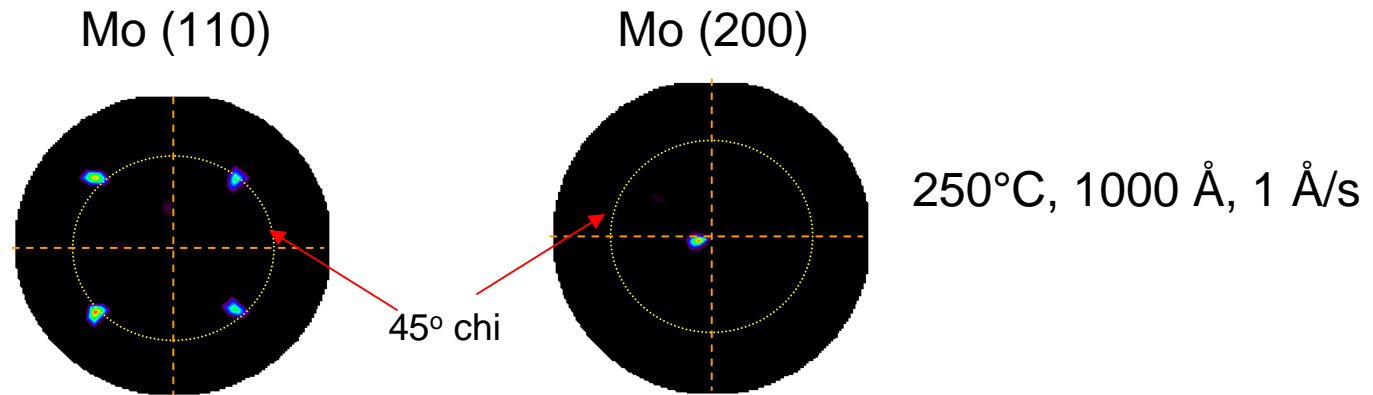


200



- Pole figure data complicated by Si signal. Mo (211) has Si (400) at center of pole figure.
- Mo deposited on Si(100) at room temperature might have bi-axial (110) out-of-plane texture.
- Mo (200) pole is complicated by Si. What we see is only the Si (311) artifact intensity.

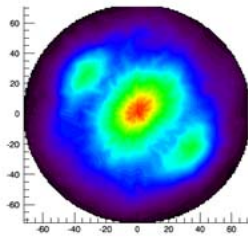
Mo on [1-102] Al₂O₃



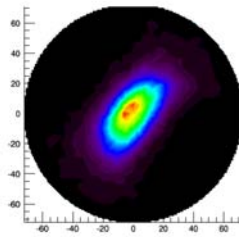
- Mo film deposited on sapphire has out-of-plane (200) texture.
- Four fold spots at 45° chi for Mo (110) indicate (200) out of plane texture and in-plane bi-axial texture for film. Note that spots are not perfectly aligned to the 45° chi ring (yellow dotted line).
- Bi-axial Mo film on Al₂O₃ [1-102]

Er deposited on rolled Mo no-etched

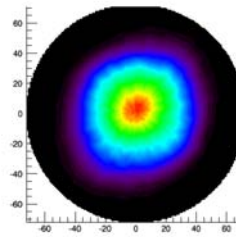
450°C, 5000 Å, 10 Å/s



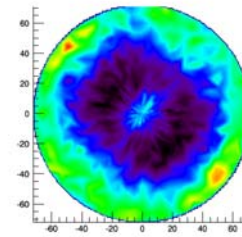
Mo (110)



Mo (200)



Er (002)

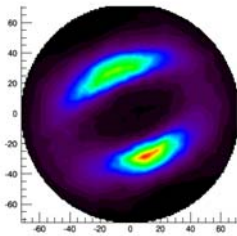


Er (100)

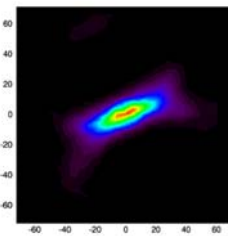
- No etched Mo substrate shows both (110) out of plane and (200) out of plane rolling texture.
- Er (002) out of plane with hint of rolling texture

Er deposited on Mo etched

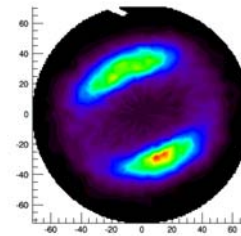
450°C, 5000 Å, 10 Å/s



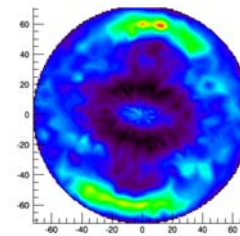
Mo (110)



Mo (200)



Er (002)

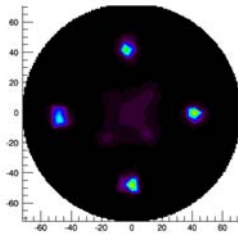


Er (100)

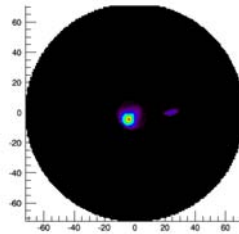
- Mo-etched substrate has (200) out of plane rolling texture. Er (002) shows rolling texture. Is Er (002) growing epitaxial on Mo (110)? Maybe
- Mo film has clear out-of plane (200) bi-axial texture.

Er on Mo on Sapphire [1-102]

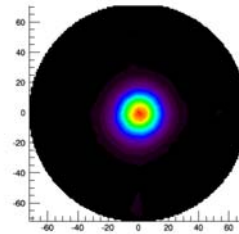
450°C, 5000 Å, 10 Å/s



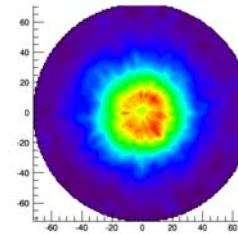
Mo (110)



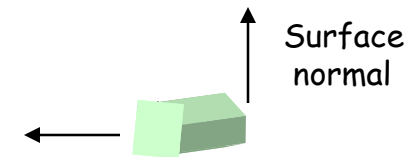
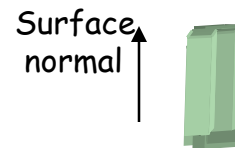
Mo (200)



Er (002)



Er (100)

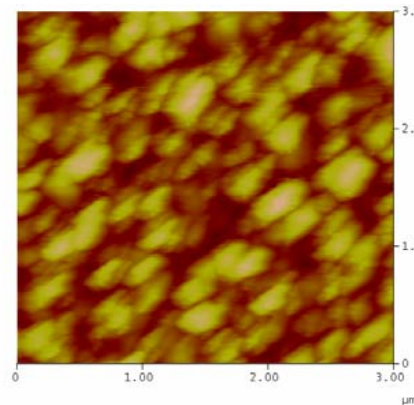


- Er film appears to have bi-modal texture with the (002) and (100) nearby out of plane.
- The Er (002) does not appear to be growing epitaxially on Mo(110) this time perhaps because of the presence Er_2O_3 ? The (100) is nearby epi on Moly.

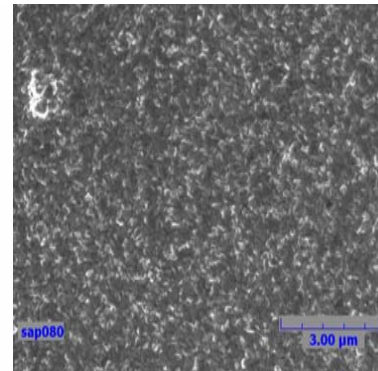
Er deposited onto various Mo substrates

Er/Mo/[1-102] Al₂O₃

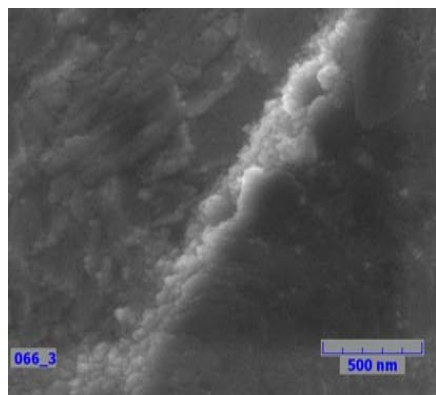
450 °C, 10 Å/s



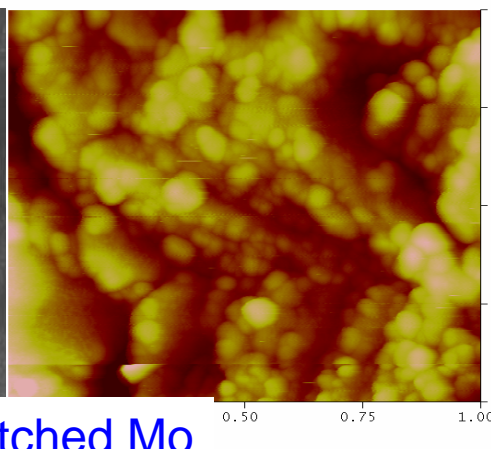
111407-3-1.00



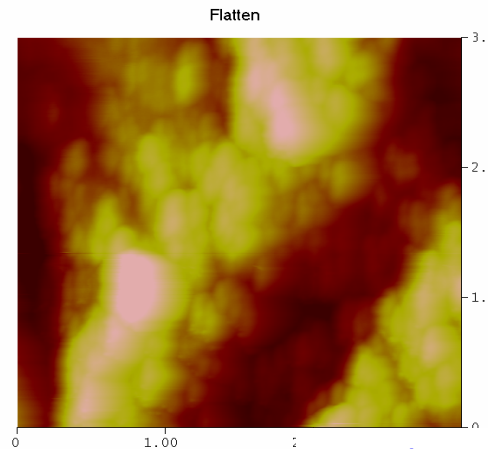
Films RMS = 10.32 nm



Er/no-etched Mo

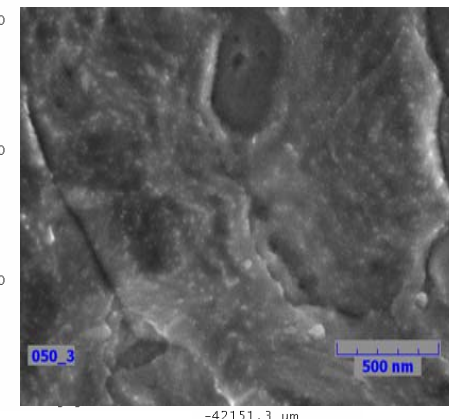


092107-6-2_f.000



111407-2-1.000

Er/etched Mo



-42151.3 μm

Summary of the influence of substrate roughness and deposition parameters on the film surface quality

- The Mo films were prepared at low deposition temperatures ($T_s/T_m=0.02-0.32$) they consist of small round grains as observed by SEM. At low temperatures the surface mobility is reduced.
- The surface roughness measured using AFM shows that the surface roughness varies with substrate and deposition rate. A faceted film is observed when deposited at 10 \AA/s on sapphire.
- AES shows that the Mo samples has a surface oxide layer $\sim 29.5 \text{ at/\%}$ and 18 at/\% in the bulk



Questions/Future Work

- A systematic study to parameterize the growth mode as a function of substrate texture and growth conditions and how that influence hydride structure
- Study the role of impurities (i.e. O_2) on film texture and residual stress